

Applicant: Alan L. Renninger et al.

PATENT APPLICATION

Serial No.: 10/717,149

Group Art Unit: 2818

Filed: November 18, 2003

Examiner: D.A. Le

For: METHOD OF FORMING A LOW VOLTAGE GATE OXIDE LAYER AND

TUNNEL OXIDE LAYER IN AN EEPROM CELL (as amended)

<u>Amendment</u>

Hon. Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office action mailed July 15, 2004, from the Patent and Trademark Office regarding the above-identified patent application, please amend the above referenced application as follows.